

Sputter-Coater

high vacuum coating system for thin film deposition



Sputter-Coater with optional instruments and side rack

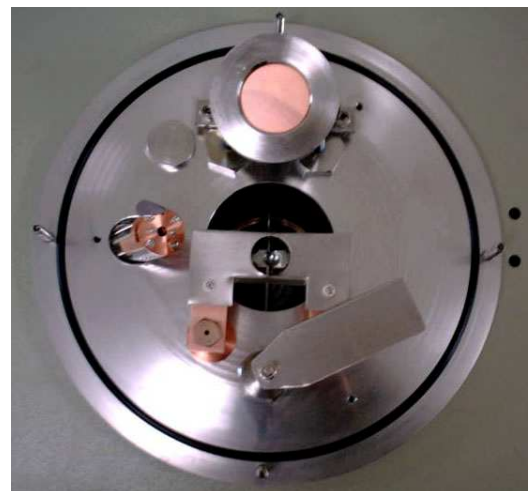
teetra enlarges its successful range of small high vacuum coating systems by the 'Sputter-Coater'. Besides the Mini-Coater which is dedicated for thermal and e-beam evaporation the Sputter-Coater serves the application where also magnetron sputter deposition is also required.

The Sputter-Coater allows the major vacuum thin film coating techniques:

- thermal evaporation
- electron beam evaporation
- sputter deposition

to be incorporated. This makes the Sputter-Coater an ideal system where utmost flexibility in deposition modes is required.

Due to its open design regarding the sample holder a wide variety of sample from several mm up to about Ø250mm can be coated. Sample holder for multiple samples can easily be considered. Further, a very big CF160 (8"OD) flange on the top position allows special sample holder systems with e.g. rotation, heating, cooling, biasing etc. even to be retrofitted by the customer.

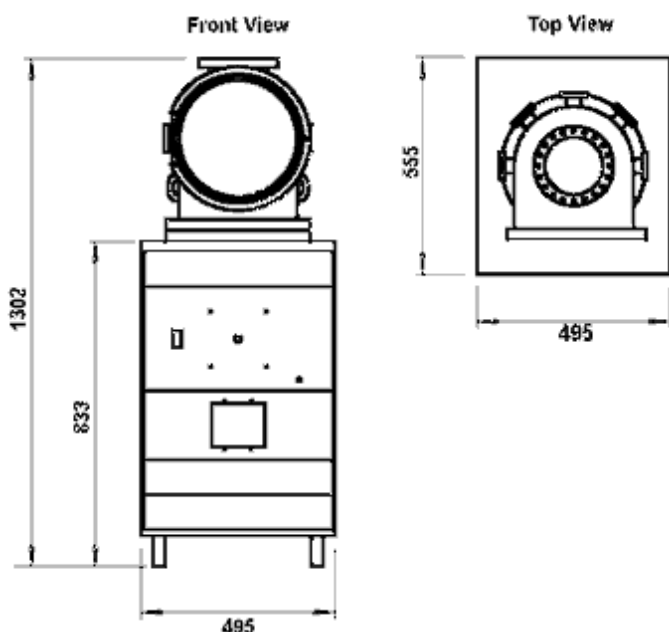


The Sputter-Coater has a 300mm quick access door which opens the full inner diameter of the vacuum chamber. Besides easy and quick sample and target exchange there are no space limitations for all kind of additions and amendments according to changing research or deposition tasks.

On the circumference of the Sputter-Coater chamber there are as standard 5 CF40 (2.75"OD) flanges provided. Typical extensions are: quartz microbalance, leak valve for sputter gas, current/thermocouples etc.. Other flange configurations are possible on special request.

The standard pumping system consists of a 260l/s turbo molecular pump with oil free membrane pump. Vacuum gauging is accomplished by a full range gauge. The entire Sputter-Coater is mounted on a 19" rack with roller casters. According to the deposition techniques mostly a side rack has to be considered.

The Sputter-Coater is a modular system which can be tailored to customer's application. Please contact us for further discussion.



Sputter Coater main rack dimensions



sputter magnetron

Specifications:

| | | | |
|--------------|--|----------------|---|
| Chamber: | Ø300mm, ca. 400mm high | Sample holder: | optional: rotation, heating, cooling, biasing |
| Pump: | 260l/s Turbo with Membrane Prepump | Sample size | up to Ø250mm |
| Gauging: | compact full range | Housing: | 19" rack on roller casters, optional side rack |
| Evaporation: | customer specified: thermal evaporation, e-beam and/or sputter deposition (2") | Size: | configuration dependant. Typical: 495mm wide, 555mm depth, 1.302mm high |

In the interest of continuous development specification may change without prior notice.